

ABSTRACT

Disclosed herein are a SSC integrated optical device and a method of manufacturing the same. When a taper waveguide in a SSC region is formed, a width and a thickness are controlled exactly by means of a selective wet etch method. In particular, a start portion of the taper waveguide is formed to have a mesa structure or a reverse-mesa structure. Accordingly, it is possible to control process parameters reproducibly, reduce the cost for an optical alignment and improve an optical coupling efficiency and quantum efficiency remarkably.